



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Attn: OIPE

Hiroyoshi TOMINAGA et al.

Application No.: 10/500,278

Docket No.: 120214

Filed: June 29, 2004

For: WAFER DOUBLE-SIDE POLISHING APPARATUS AND DOUBLE-SIDE
POLISHING METHOD

REQUEST FOR CORRECTION OF PALM RECORDS

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Attached is a photocopy of the original filing receipt on which errors have been corrected in red. These errors are being brought to the attention of the Patent and Trademark Office so that it may correct its records.

Respectfully submitted,

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WPB:JOC/mlo

Date: March 2, 2005

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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/500,278	06/29/2004	3723	1828	120214	10	37	10

25944
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CONFIRMATION NO. 9347

FILING RECEIPT



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Date Mailed: 02/17/2005

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Assignment For Published Patent Application

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Domestic Priority data as claimed by applicant

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Foreign Applications

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JAPAN 2002-91207 03/28/2002

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Non-Publication Request: No

Early Publication Request: No

Title

wafer double - side polishing
~~Double side polishing device for wafer and double side polishing method~~

Preliminary Class

451

apparatus and double-side polishing
 method

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